



U.S.S.N. 09/941,537

+ IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Chen et al.

Group Art Unit: 1756

Serial No.: 09/941,537

Examiner: J. S. Ruggles

Filed: 08/29/2001

In Response to Office Action
Dated: 04/06/2004

For: METHOD FOR REDUCING LIGHT REFLECTANCE IN A PHOTOLITHOGRAPHIC
DUAL DAMASCENE TRENCH PATTERNING PROCESS

Attorney Docket No.: 67,200-477

EXPRESS MAIL CERTIFICATE

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I hereby certify that this paper, in triplicate, is being deposited with the United States Postal Service "Express Mail Post Office to Addressee" service under 37 CFR §1.10 on the date indicated above and is addressed to: Mail Stop: Appeal, Commissioner for Patents, Alexandria, VA 22313-1450


Kathy Dixon

SUPPLEMENTAL AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, Va 22313-1450

Dear Sir:

In response to Advisory Actions mailed 04/06/2004

Applicants respectfully request entry of the following amendments to place the Application to remove issues from Appeal and comply with Examiners requirements and/or suggestions. Please consider the following remarks.